

	Type	L#	Hits	Search Text	DBs	Time Stamp	Comm	Error	Definition	Er
1	BRS	L1	1	"6517977".PN	USPA	2004/12/07 T: 21:09	USO CR			
2	BRS	L2	1	"6334960".PN	USPA	2004/12/07 T: 21:10	USO CR			
3	BRS	L3	1	"6234379".PN	USPA	2004/12/07 T: 21:10	USO CR			
4	BRS	L4	1	"6180239".PN	USPA	2004/12/07 T: 21:10	USO CR			
5	BRS	L5	1	"5277749".PN	USPA	2004/12/07 T: 21:11	USO CR			
6	BRS	L6	1	"4832790".PN	USPA	2004/12/07 T: 21:11	USO CR			
7	BRS	L7	1	"4731155".PN	USPA	2004/12/07 T: 21:11	USO CR			
8	BRS	L8	1	"4606788".PN	USPA	2004/12/07 T: 21:12	USO CR			
9	BRS	L9	1	"4731155".PN	USPA	2004/12/07 T: 21:12	USO CR			
10	BRS	L10	1	"4832790".PN	USPA	2004/12/07 T: 21:12	USO CR			
11	BRS	L11	1	"4832790".PN	USPA	2004/12/07 T: 21:12	USO CR			
12	BRS	L12	1	"4576678".PN	USPA	2004/12/07 T: 21:13	USO CR			

Type	Hits	Search Text	DBs	Time Stamp	Comments	Error Defn	Errors	Ref #
1 BRS	0	mold and nanoimprint and database and in <i>near</i> <i>situ</i> and pattern and mark\$3	US-PGPUB; USPAT	2004/12/07 15:50				S1
2 BRS	1	mold and nanoimprint and database	US-PGPUB; USPAT	2004/12/07 15:51				S2
3 BRS	100	mold and nanoimprint	US-PGPUB; USPAT	2004/12/07 15:52				S3
4 BRS	62	S3 and pattern and source	US-PGPUB; USPAT	2004/12/07 15:52				S4
5 BRS	21	S4 and deformation	US-PGPUB; USPAT	2004/12/07 15:53				S5
6 BRS	6	S5 and "in-situ"	US-PGPUB; USPAT	2004/12/07 17:04				S6
7 IS&R	2	(("5772905") or ("6309580")).PN	US-PGPUB; USPAT	2004/12/07 17:04				S7

Document ID	Issue Date	Pages	Title	Current OR	Current XR	Retrieval C	Inventor	S	C	P	U	I	Y
US 20040219249 A1	20041104		Uniform pressing apparatus	425/385			Chung, Yong-Chen et al.	C	F	F	F	C	F
US 20040188381 A1	20040930	12	Positive tone bi-layer imprint lithography method	216/40			Sreenivasan, Sidigata V	C	F	F	F	C	F
US 20040170771 A1	20040902	55	Method of creating a dispersion of a liquid on a substrate	427/421.1			Bailey, Todd et al.	C	F	F	F	C	F
US 20040168586 A1	20040902	54	Imprint lithography template having a feature size under 250 nm	101/3.1	355/18		Bailey, Todd et al.	C	F	F	F	C	F
US 20040143958 A1	20040729		Methods for making data storage media and the resultant media	29/602.1	29/818		Feist, Thomas P. et al.	C	F	F	F	C	F
US 20040141163 A1	20040722	57	Device for holding a template for use in imprint lithography	355/18	355/75		Bailey, Todd et al.	C	F	F	F	C	F
US 20040131718 A1	20040708		Lithographic apparatus for fluid pressure imprint lithography	425/385			Chou, Stephen Y. et al.	C	F	F	F	C	F
US 20040076822 A1	20040422		Fibrillar microstructure for conformal contact and adhesion	428/364			Jagota, Anand et al.	C	F	F	F	C	F
US 20040036201 A1	20040226		Methods and apparatus of field-induced pressure imprint lithography	264/402	264/320, 425/174, 425/406		Chou, Stephen Y. et al.	C	F	F	F	C	F
US 20040013982 A1	20040122		Fabrication of finely featured devices by liquid embossing	430/320	257/E21.024, 257/E21.174, 257/E21.577, 264/I.1, 264/I.24, 264/I.36, 264/I.38,		Jacobson, Joseph M. et al	F	F	F	F	F	F
US 20030219992 A1	20031127		Replication and transfer of microstructures and nanostructures	438/748			Schaper, Charles Daniel	F	F	F	F	F	F
US 20020115002	20020822	34	Template for room temperature, low pressure	430/5	355/18, 430/17,		Bailey, Todd et al.						

	A1		micro-and nano-imprint lithography		430/22; 430/30						
13	US 20020081460 A1	20020627	Data storage media	428/694ST			Feist, Thomas P. et al.				
14	US 20020080712 A1	20020627	Method for retrieving data from a storage media	720/718			Feist, Thomas P. et al.				
15	US 20020048691 A1	20020425	Data storage media	428/694ML			Davis, John E. et al.				
16	US 20020025408 A1	20020228	Embossing method and article formed therefrom	428/141	264/293; 264/322		Davis, John E.				
17	US 20020020484 A1	20020221	Methods for making data storage media and the resultant media	156/196	204/192.12; 205/317; 264/134; 264/279; 360/135; 369/283; 369/288;		Feist, Thomas P. et al.				
18	US 6752952 B2	20040622	Embossing methods	264/293	264/322		Davis, John E.				
19	US 6715200 B2	20040406	Methods for making data storage media	29/604	264/319; 264/320; 264/322; 29/592.1; 29/602.1; 29/856; 29/858;		Feist, Thomas P. et al.				
20	US 6696220 B2	20040224	Template for room temperature, low pressure micro-and nano-imprint lithography	59	430/272.1	101/473; 430/275.1; 430/302; 430/320	Bailey, Todd et al.				
21	US 6517995 B1	20030211	Fabrication of finely featured devices by liquid embossing	430/320	101/28; 257/E21.024; 257/E21.174; 257/E21.577; 264/1.1; 264/1.24; 264/1.36;		Jacobson, Joseph M. et al.				

U	Document ID	Issue Date	Pages	Title	Current OR	Current XR	Retrieval C	Inventor	S	C	I	U	S
1	US 20040188381 A1	20040930	12	Positive tone bi-layer imprint lithography method	216/40			Sreenivasan, Sidgata V.	o	o	o	o	o
2	US 20040170771 A1	20040902	55	Method of creating a dispersion of a liquid on a substrate	427/421.1			Bailey, Todd et al.	o	o	o	o	o
3	US 20040168586 A1	20040902	54	Imprint lithography template having a feature size under 250 nm	101/3.1	355/18		Bailey, Todd et al.	o	o	o	o	o
4	US 20040141163 A1	20040722	57	Device for holding a template for use in imprint lithography	355/18	355/75		Bailey, Todd et al.	o	o	o	o	o
5	US 20020115002 A1	20020822	34	Template for room temperature, low pressure micro-and nano-imprint lithography	430/5	355/18; 430/17; 430/22; 430/30		Bailey, Todd et al.	o	o	o	o	o
6	US 6696220 B2	20040224	59	Template for room temperature, low pressure micro-and nano-imprint lithography	430/272.1	101/473; 430/275.1; 430/302; 430/320		Bailey, Todd et al.	o	o	o	o	o

U	1	Document ID	Issue Date	Pages	Type	Current OR	Current XR	Retrieval C	Inventor	S	C	P	RS	RS
1		US 6309580	20011030	20	Release surfaces, particularly for use in nanoimprint lithography	264/338	216/44; 216/52; 216/53		Chou, Stephen Y.	<input type="checkbox"/>				
2		US 5772905 A	19980630	14	Nanoimprint lithography	216/44	216/52; 216/53; 438/691; 438/700; 438/735		Chou, Stephen Y.	<input type="checkbox"/>				